

# **New Test Vehicle with a Variety of Programmed ML Defects for EUV Blanks Inspection**

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- **Background**
- **Motivation**
- **Experiment**
- **Results**
- **Summary**
- **References**

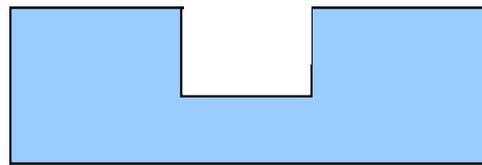
- Recently EUV mask yield and defect inspection are strongly focused in the industry.

Technical Issue on EUV Lithography					
Rank	2007	2008	2009	2010	2011
1	Source	Source	Mask	Mask	Source
2	Resist	Mask	Source	Source	Mask
3	Mask	Resist	Resist	Resist	Resist

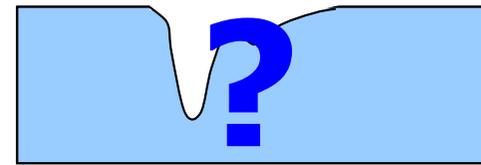
2011 EUVL Symposium SEMATECH

- Multilayer defect is one of the key issue that EUV mask/blank industry has to overcome. However, there are some difficulties.
- Target defect size is  $\sim 1\text{nm}$  height level according to several researches.
  - Big challenges for defect inspection
- Curious results have been reported that defect printability and detectability of rectangle shape defects (programmed defect) and natural defects are very different.

- Need to consider how to obtain appropriate test blanks with programmed ML defects for future tool evaluation and qualification.



Programmed defect  
(rectangle shape)



Natural

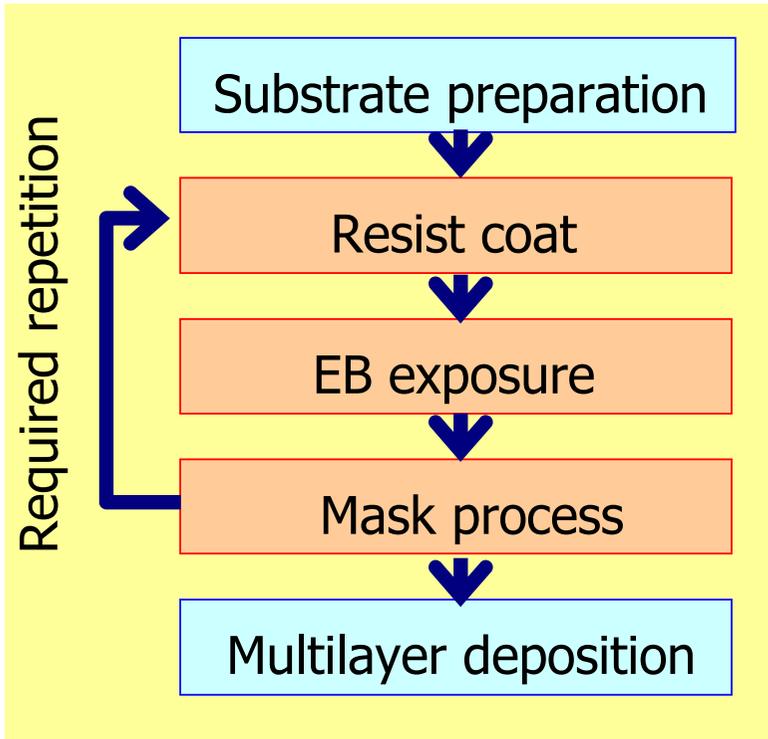
- How can targeted 1nm order defects be fabricated with high accuracy?
- How can 'Natural-like' programmed defects be fabricated?
- Rectangle shape defects may not be appropriate to reproduce real situation of 'Natural' defects.



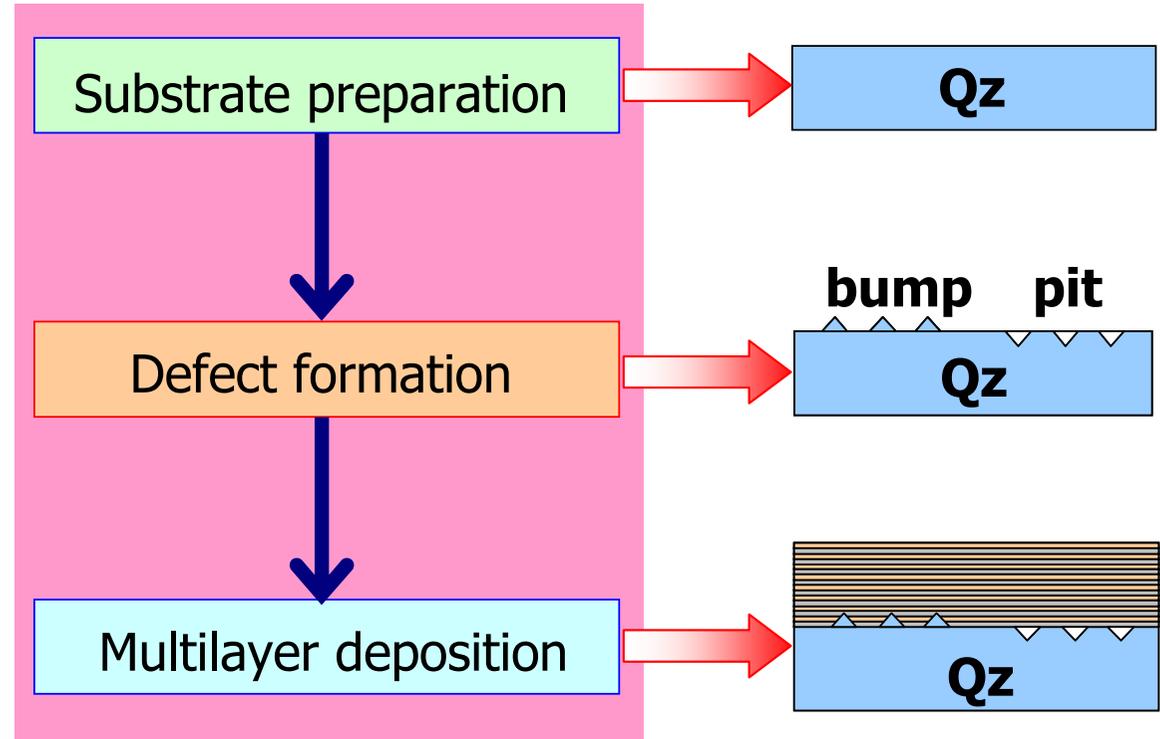
**✓ Propose new programmed ML defect fabrication method and verify the effectiveness of the method.**

## ■ Programmed defect blank fabrication procedure

● Conventional procedure



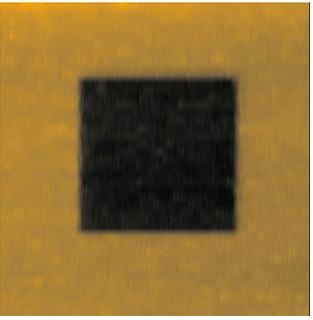
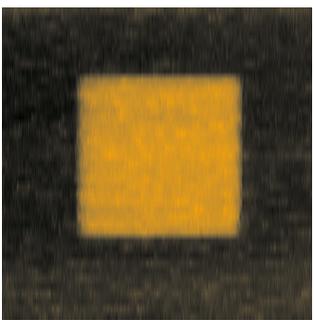
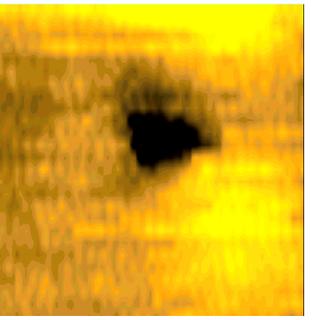
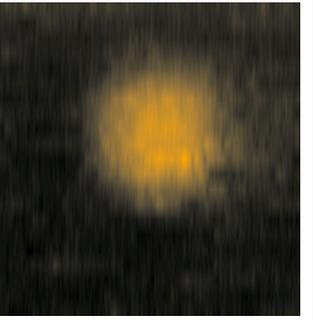
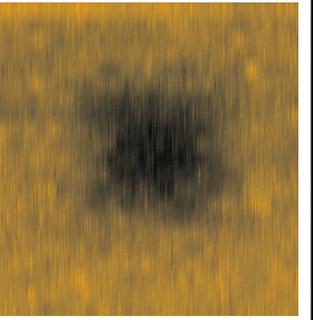
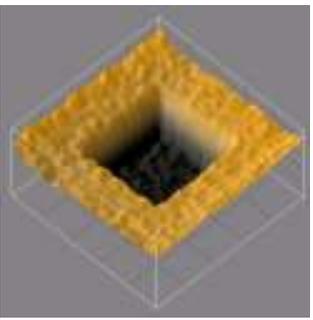
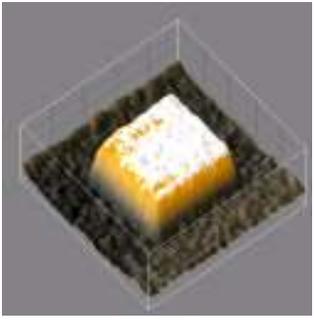
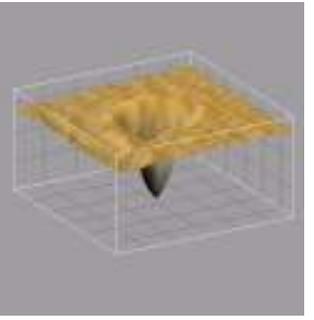
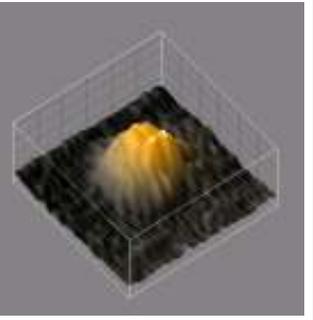
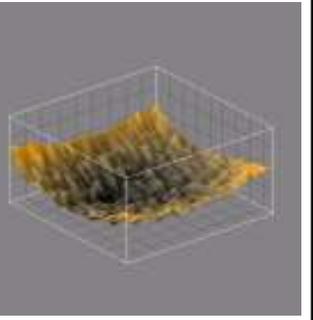
● New procedure



- **Conventional procedure** : Need to repeat defect formation process to fabricate all designed defect height.
- **New procedure** : **Simple & flexible defect fabrication process**

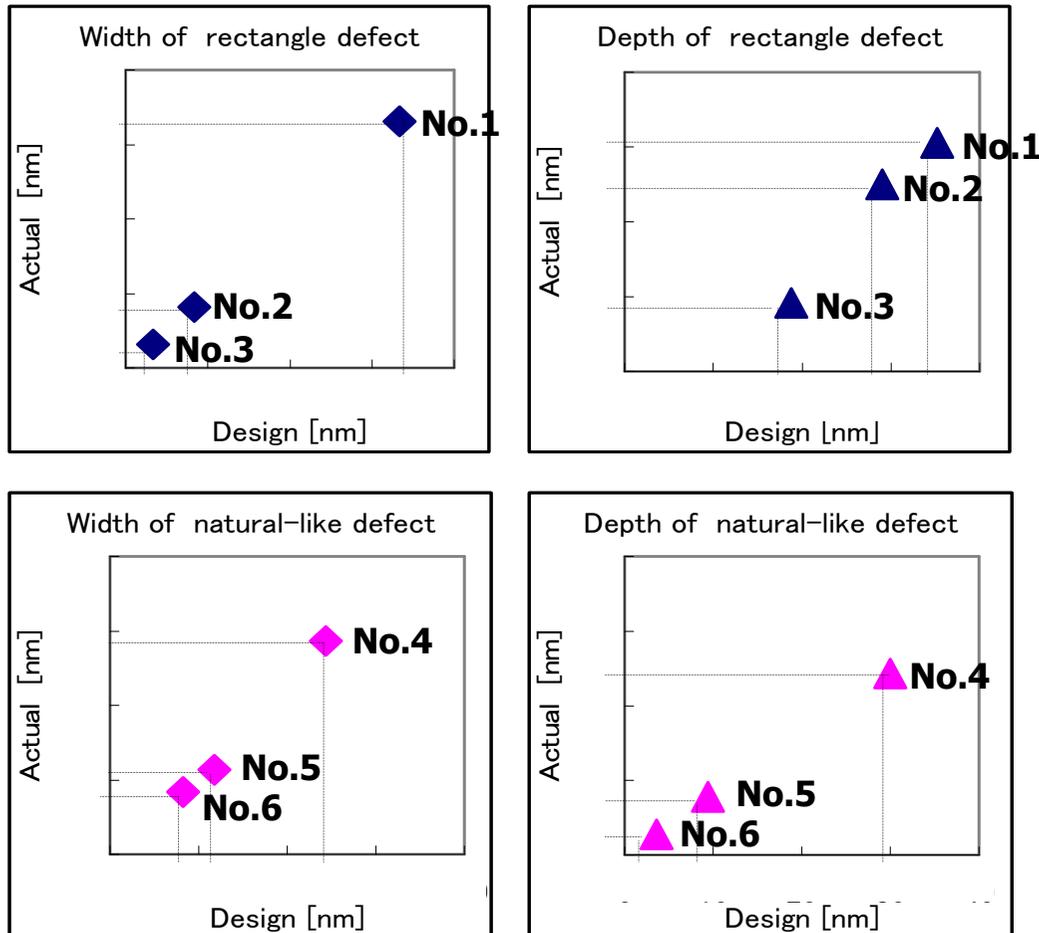
✓ **Programmed defect blank was fabricated with proposed new fabrication procedure.**

- Both rectangle shape defects and natural-like defects were fabricated by new method.

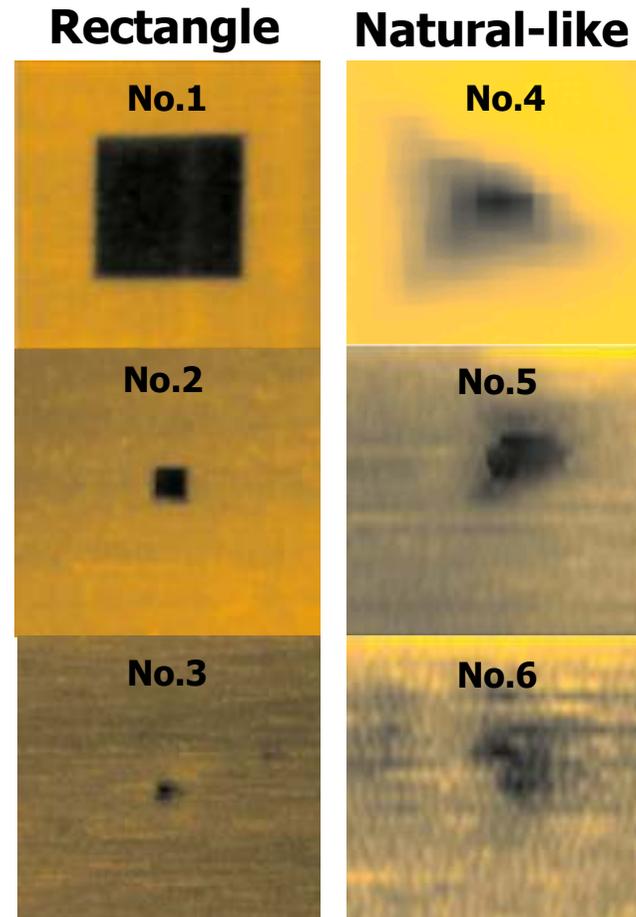
Defect Type	Rectangle Pit	Rectanble Bump	Natural-like Pit	Smooth-edge Bump	Smooth-edge Pit
2D Image					
3D Image					

- ✓ Attempted to reproduce rectangle shape defects similar to the defects which conventional method fabricates.
- ✓ Natural-like and smooth-edge defects are supposed to be similar to a shape of real substrate defects.

## Programmed defect size between design and measured.



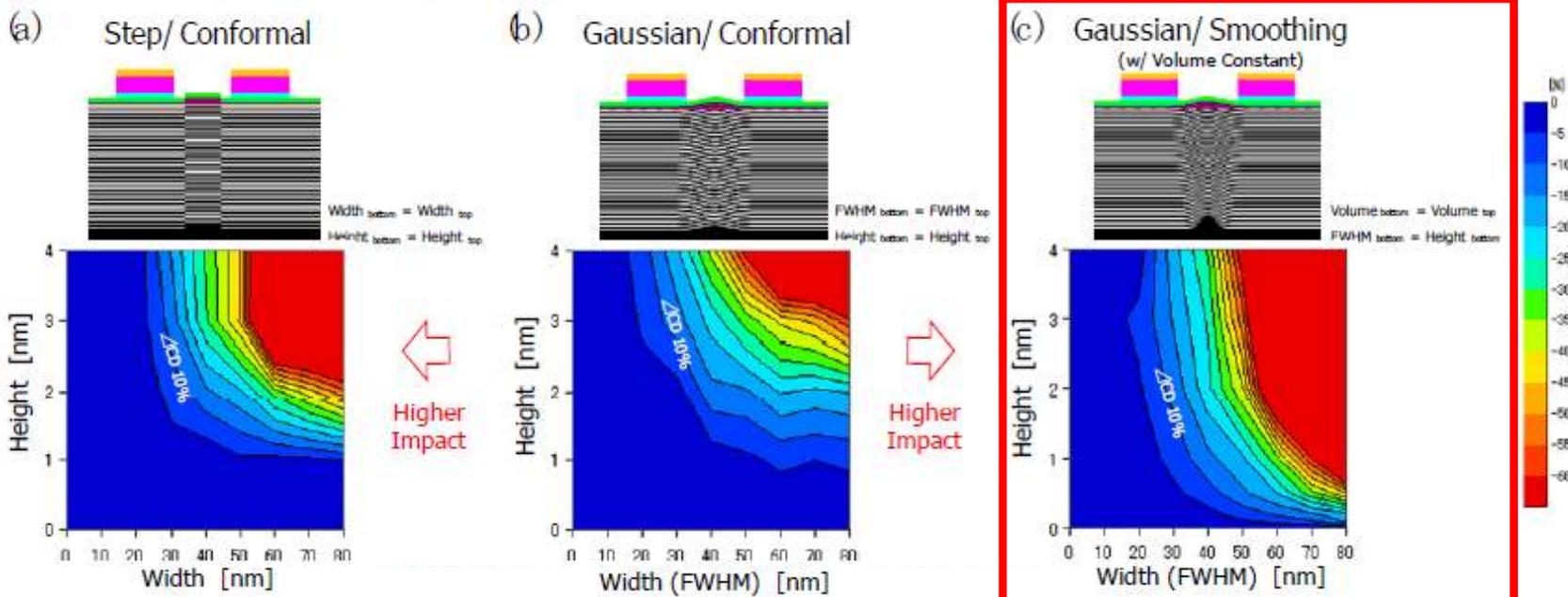
## AFM image



◆ **Confirmed linear relation between design and measured size.**

- ✓ **Source of the ML defects were successfully fabricated.**
- ✓ **Confirmed fabricated defect sizes were well controlled by the new method as expected.**

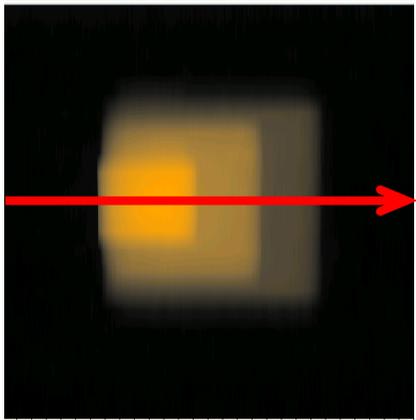
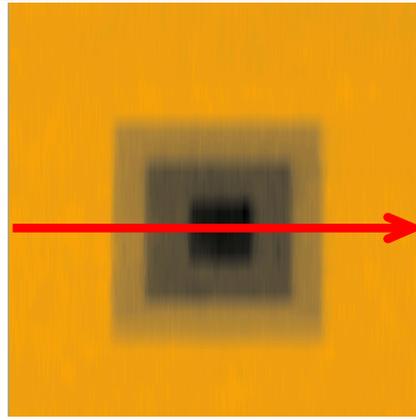
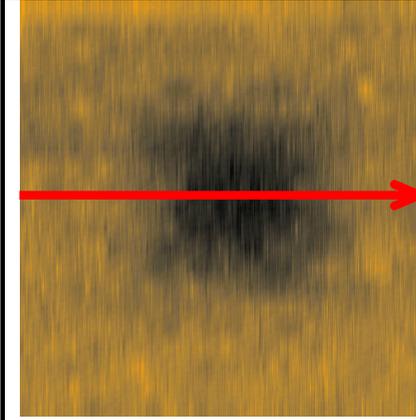
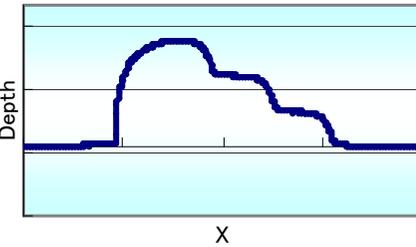
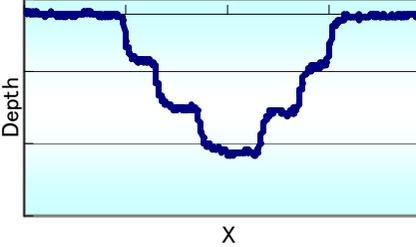
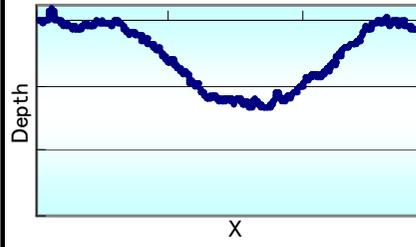
- Selete reported printability of ML defects depends on ML defect structure.



\*Source SELETE at SPIE2011

- ✓ Generally small size of ML defects have been focused on ML defect printability study.
- ✓ Wide defect below 1nm height can be critical on some defect structure model.
  - Light up shallow and complicated defect structures.

- Tested to fabricate other types of defect shapes to confirm flexibility of the new procedure.

Defect Type	Multi Step		Smooth-edge
	Bump	Pit	Pit
2D Image			
Cross Section			

- ✓ Confirmed very unique defect shapes were fabricated by application of the new defect fabrication method.
- ✓ Expected to be capable to reproduce real defect situation.

- Compared defect shape before and after ML deposition of fabricated defects.

Defect Type	Rectangle Pit		Natural-like Pit		Smooth-edge Pit	
	Bottom	Top	Bottom	Top	Bottom	Top
2D Image						
Cross Section						
Deposition Model	<b>Semi-smoothing</b>		<b>Smoothing</b>		<b>Conformal</b>	

— :  
**Bottom**

— :  
**Top**

- ✓ Defect shape transition model is very complicating.
- ✓ Difficult to predict how ML defect shape grows from the bottom to the top of Multilayer.

- Compared test blank manufacturability between conventional and new method.

Items		Conventional Method	New Method
Manufacturability	Defect height control		
	Defect quantity		
	Defect type		
	Process complexity		



: Excellent

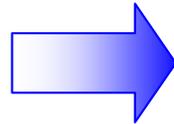


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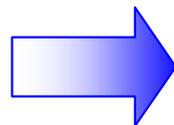
: Unsuitable

◆ Conventional



- Easy to fabricate many same height defects.
- Long and complex defect formation process
- Only rectangle shape defects

◆ New Method



- Can fabricate many types and sizes.
- Simple defect formation process
- Not good to duplicate exact same defect a lot.

■ Suitability for purpose of test blank usage

Items		Conventional Method	New Method
Purpose of use	Quantification		
	Tool control		
	Algorithm development & optimization		
	Defect review function development		

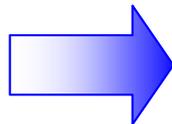


: Excellent



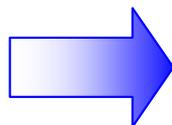
: Good

◆ Conventional



- Easy to quantify defects due to its' rectangle shape.
- Rectangle shape defects are totally different from Natural defect shape.

◆ New Method



- Natural-like defects can reproduce similar situation as real defects.
- May not be easy to quantify some defect types due to its' complex shape.

- **Source of defects were fabricated on substrate by newly developed methods.**
- **Attempted to fabricate very unique shape defects.**
  - ✓ Succeeded to fabricate very shallow defects with 0.1nm depth.
  - ✓ Showed flexibility of defect source fabrication.
- **Confirmed different defect structure models were reproduced on the fabricated test blank.**
  - ✓ Supposed defect structure model is very complicating.
- **New programmed defect fabrication method showed good effectiveness to provide proper test vehicle.**
  - ✓ Further evaluation for inspection and printability test with the fabricated vehicle will be expected.
- **The defect fabrication technique is expected to be useful for future tool development.**

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